

# Abdullah H Alshehri

## List of Publications by Year in descending order

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6  
papers

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citations

1684188

5  
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1872680

6  
g-index

6  
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6  
docs citations

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times ranked

86  
citing authors

#	ARTICLE	IF	CITATIONS
1	Quantum-Tunneling Metal-Insulator-Metal Diodes Made by Rapid Atmospheric Pressure Chemical Vapor Deposition. <i>Advanced Functional Materials</i> , 2019, 29, 1805533.	14.9	39
2	Near zero-bias MIIM diode based on TiO <sub>2</sub> /ZnO for energy harvesting applications. <i>AIP Advances</i> , 2019, 9, .	1.3	18
3	Nanoscale Film Thickness Gradients Printed in Open Air by Spatially Varying Chemical Vapor Deposition. <i>Advanced Functional Materials</i> , 2021, 31, 2103271.	14.9	8
4	Metal-Insulator-Insulator-Metal Diodes with Responsivities Greater Than 30 A W <sup>-1</sup> Based on Nitrogen-Doped TiO <sub>x</sub> and AlO <sub>x</sub> Insulator Layers. <i>Advanced Electronic Materials</i> , 2021, 7, 2100467.	5.1	7
5	Simple plasma assisted atomic layer deposition technique for high substitutional nitrogen doping of TiO <sub>2</sub> . <i>Journal of Vacuum Science and Technology A: Vacuum, Surfaces and Films</i> , 2018, 36, 031602.	2.1	5
6	Metal-Insulator-Metal Diodes: Quantum-Tunneling Metal-Insulator-Metal Diodes Made by Rapid Atmospheric Pressure Chemical Vapor Deposition ( <i>Adv. Funct. Mater.</i> 7/2019). <i>Advanced Functional Materials</i> , 2019, 29, 1970042.	14.9	1